



EMICON SA



PLASMA MONITOR AND
PROCESS CONTROL SYSTEM



STAND-ALONE SPECTROSCOPIC PLASMA MONITOR SYSTEM FOR INDUSTRIAL PRODUCTION LINES

Highlight Features:

- Up to 8 spectrometer units for data acquisition at different machine locations
- Input of up to 8 external voltage signals (e.g. from lambda probe, target voltage,...)
- Stand-alone operation by means of integrated processor unit
- Integrated touch panel display for on-site information and settings
- Communication by industrial standard interfaces (LAN, Profibus, IOs, ...)

Your Benefits:

- Upgrade your production line for increasing product quality or producing high-end products
- Stabilize process by simultaneous PID control e.g. of gas flow control and target voltage
- Control and compensate target erosion in sputter applications
- Retrofit your existing PEM for enhanced productivity
- Integrate as stand-alone system in machine control

DATA SHEET

Number of spectrometer channels	1 - 8
Spectral range	200 - 1100 nm (totally covered by each spectrometer)
Number of wavelength channels	unlimited (selected by software without hardware modification)
Analysis of monitor tracks	single, combined (+, -, /, *), ratio, average, integral
Spectral resolution	1.5 nm FWHM
Minimum time resolution	1 ms
Detector	CCD array with 16 Bit A/D converter
Optical fiber connector	SMA 905
Analog inputs	2 (4, 8) x 0-10 volts (iCoupler)
Analog outputs	4 (8) x 0-10 volts (iCoupler)
Digital outputs	8 (16) x TTL / 24V (Opto-Coupler)
Digital inputs	8 (16) x TTL / 24V (Opto-Coupler)
Remote control interfaces	LAN, digital inputs, (Profibus)
Processor unit	Integrated MPU with EMCON SA operation system
Display	5,7" color touch panel (resistive)
Power supply	5 VDC 4A
Housing	19" rack mount box (4U, 84HP)
Dimensions [mm]	480(w) x 190(h) x 420(d)
Weight [kg]	3.5

EMICON SA Manager software on Windows® XP / 7 / 8

